Appl. No. 10/758,384
Amdt. dated December 7, 2005
Reply to Office action of September 7, 2005

Amendments to the Claims:

Please amend the claims as indicated.

1. (Currently Amended) A patterning system comprising:

a bifurcated heat transfer mechanism having a surface; and

a source ~~of radiation~~ to direct thermal ~~radiation~~ energy toward said bifurcated heat transfer mechanism, with said bifurcated heat transfer mechanism collecting said thermal ~~radiation~~ energy and conducting said thermal ~~radiation~~ energy to said surface.

2. (Original) The system as recited in claim 1 wherein said bifurcated heat transfer mechanism further includes developing a localized heat source proximate to said surface.

3. (Currently Amended) The system as recited in claim 1 wherein said system further includes a mold positioned between said bifurcated heat transfer mechanism and said source ~~of radiation~~ to allow said ~~radiation~~ energy to propagate ~~there through~~ therethrough.

4. (Currently Amended) The system as recited in claim 1 wherein said system further includes an imprinting layer positioned between said bifurcated heat transfer mechanism and said source ~~of radiation~~ to allow said thermal ~~radiation~~ energy to propagate ~~there through~~ therethrough.

5. (Original) The system as recited in claim 1 wherein said bifurcated heat transfer mechanism comprises a carbon black composition.

6. (Original) The system as recited in claim 1 wherein said bifurcated heat transfer mechanism is permanently disposed within said system.

7. (Original) The system as recited in claim 1 wherein said bifurcated heat transfer mechanism is removably disposed within said system.

8. (Currently Amended) A patterning system comprising:

a source of radiation to direct radiation toward a target;

a wavelength discriminator to selectively allow first and second subsets of said radiation to reach said target, with said first subset including thermal energy; [[and]]

a mold positioned to allow said first and second subsets to propagate there through; and

a thermal absorption layer, having a surface, disposed to collect said first subset and [[to]] develop a localized heat source therein having heat energy associated therewith, with said heat source conducing said heat energy to said surface while maintaining a constant phase state.

9. (Original) The system as recited in claim 8 wherein said system further includes an imprinting layer positioned between said mold and said thermal absorption layer to allow said first subset to propagate there through.

10. (Original) The system as recited in claim 8 wherein said thermal absorption layer comprises a carbon black composition.

11. (Original) The system as recited in claim 8 wherein said thermal absorption layer is permanently disposed within said system.

12. (Original) The system as recited in claim 8 wherein said thermal absorption layer is removably disposed within said system.

13. (Original) The system as recited in claim 8 wherein said constant phase state comprises a solid phase state.

14. (Currently Amended) A patterning system comprising:

a source of radiation to direct radiation, having multiple wavelengths including thermal radiation, along a path, with said path extending between said source and a target;

a wavelength discriminator to selectively allow a subset of said radiation to travel toward said target; and

a bifurcated heat transfer mechanism having a surface disposed between said wavelength discriminator and said target to collect said thermal radiation and [[to]] develop heat energy therein, and to conductively transfer said heat energy ~~from said thermal absorption layer~~ to said surface.

15. (Original) The system as recited in claim 14 wherein said system further includes a mold positioned between said bifurcated heat transfer mechanism and said source of radiation to allow said radiation to propagate there through.

16. (Original) The system as recited in claim 14 wherein said system further includes an imprinting layer positioned between said bifurcated heat transfer mechanism and said source of radiation to allow said thermal radiation to propagate there through.

17. (Original) The system as recited in claim 14 wherein said bifurcated heat transfer mechanism comprises a carbon black composition.

18. (Original) The system as recited in claim 14 wherein said bifurcated heat transfer mechanism is permanently disposed within said system.

19. (Original) The system as recited in claim 14 wherein said bifurcated heat transfer mechanism is removably disposed within said system.

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